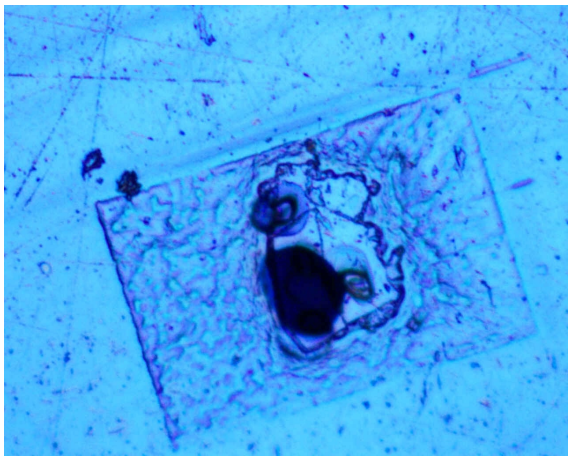
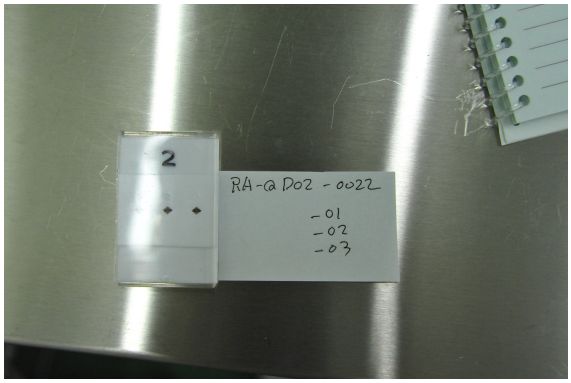
# RA-QD02-0022

| Status | Date | Size | Transfer | Category | Phase |
|---|---|---|---|---|---|
| Curation glovebox2, PS | | 50μm | Curation N2-SP3, glovebox2 | 1 | lpx, ol, FeS |



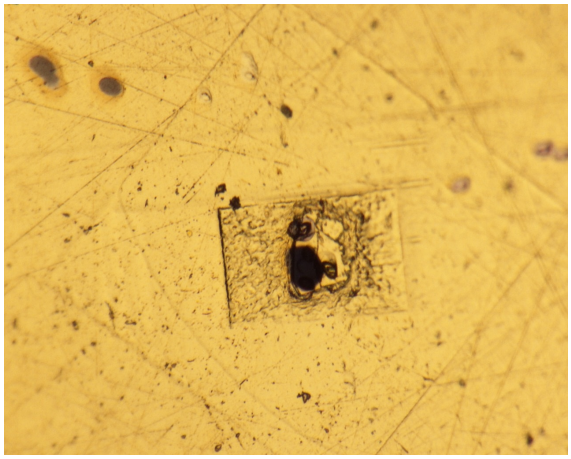
20120221/TEMreturnSamplecheck/20120221/RA-QD02-0022x500.jpg

SAMPLE : RA-QD02-0022
PREID :
PROCESS : condition check after initial analysis
OPERATOR : Yada, Uesugi
COMMENT :



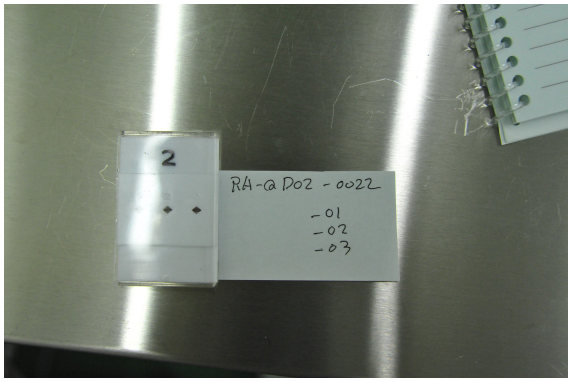

20140513/returnSamplecheck/D700/DSC_0134.JPG

SAMPLE : RA-QD02-0022-01_03
PREID :
PROCESS : sample check
OPERATOR : Uesugi
COMMENT : UTS by ultramicrotome



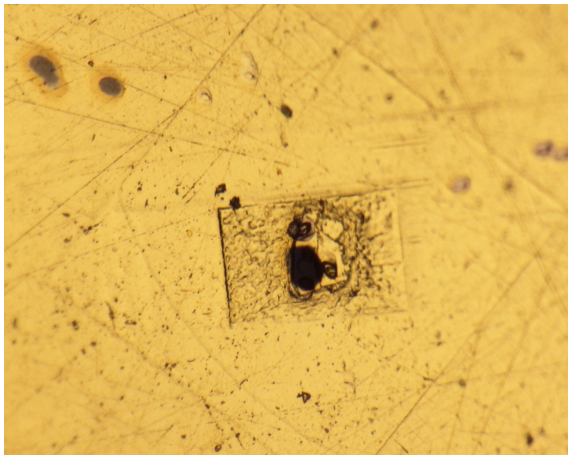
20140513/returnSamplecheck/opt/04-RA-QD02-0022.jpg

SAMPLE : RA-QD02-0022
PREID :
PROCESS : sample check
OPERATOR : Uesugi
COMMENT : polished section with SIMS hole



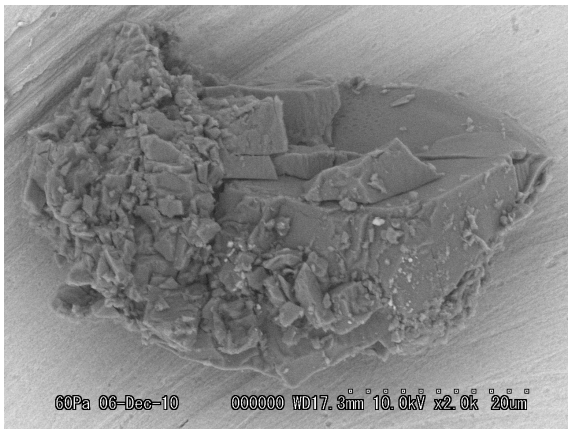

20140513/returnSamplecheck/D700/DSC_0134.JPG

SAMPLE : RA-QD02-0022-01_03
PREID :
PROCESS : sample check
OPERATOR : Uesugi
COMMENT : UTS by ultramicrotome



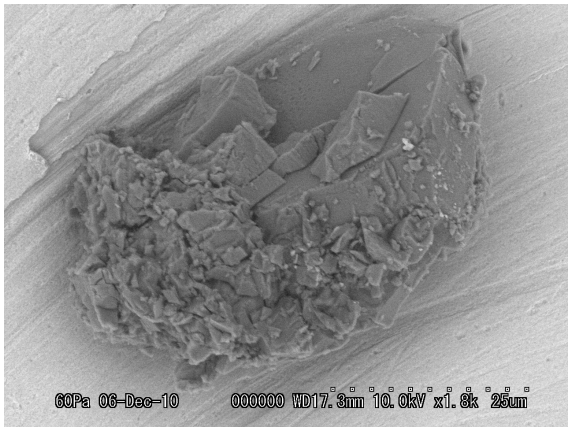
20140513/returnSamplecheck/opt/04-RA-QD02-0022.jpg

SAMPLE : RA-QD02-0022
PREID :
PROCESS : sample check
OPERATOR : Uesugi
COMMENT : polished section with SIMS hole



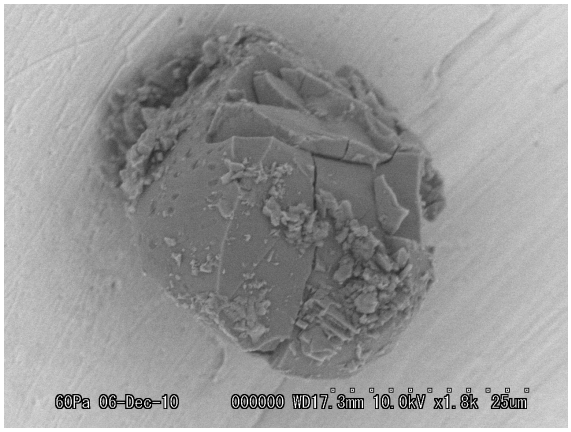

20101206/SEM/BSE/unid10_02.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : BSE
OPERATOR : Nakamura, Noguchi
COMMENT :



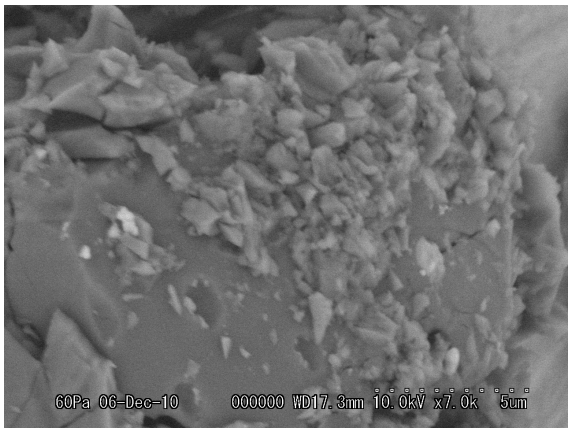

20101206/SEM/BSE/unid10_03.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : BSE
OPERATOR : Nakamura, Noguchi
COMMENT :



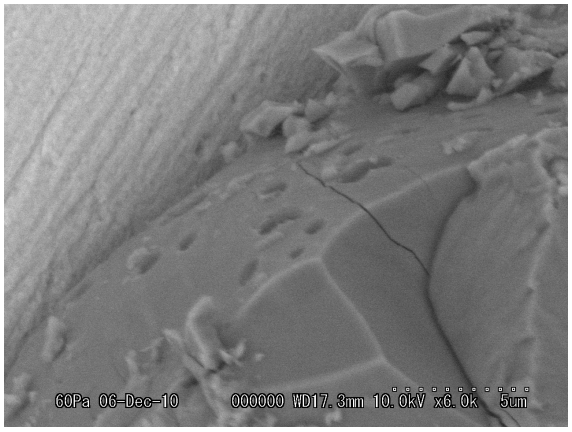

20101206/SEM/BSE/unid10_04.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : BSE
OPERATOR : Nakamura, Noguchi
COMMENT :




20101206/SEM/BSE/unid10_05.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : BSE
OPERATOR : Nakamura, Noguchi
COMMENT :

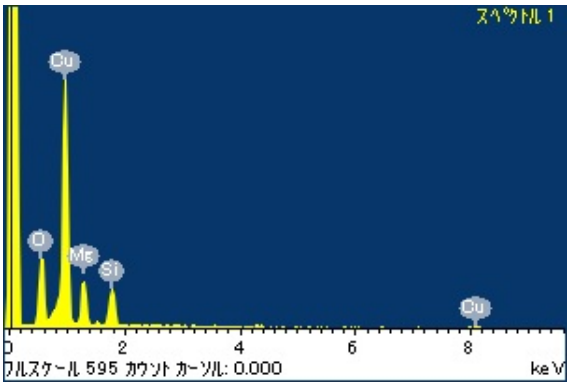


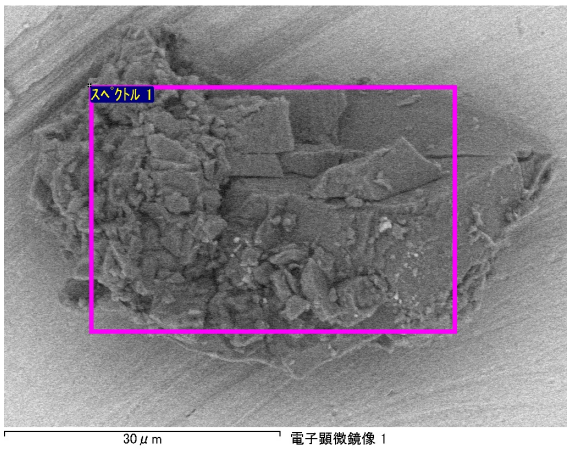

20101206/SEM/BSE/unid10_06.bmp

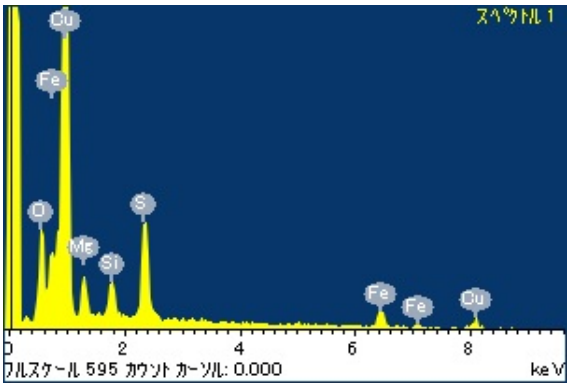
SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : BSE
OPERATOR : Nakamura, Noguchi
COMMENT :

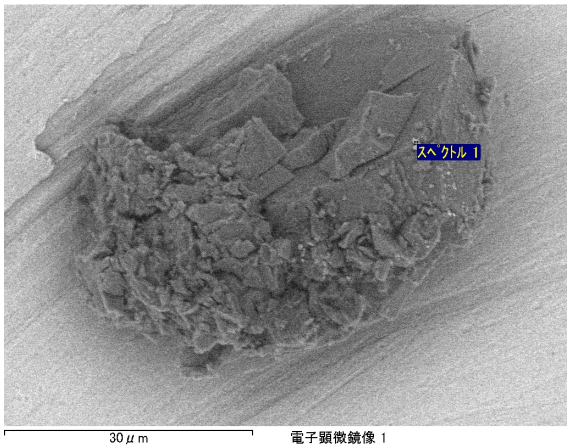
20101206/SEM/EDS/RA-QD02-0022.docx

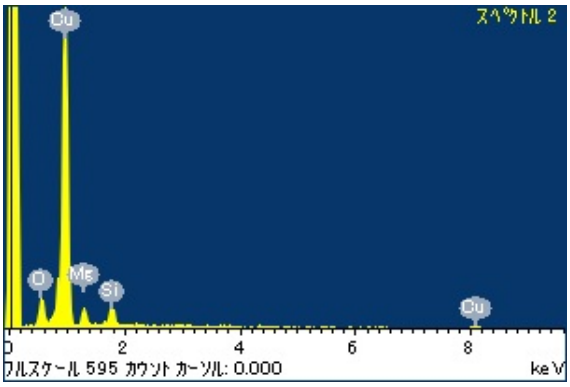
SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : EDS
OPERATOR : Nakamura, Noguchi
COMMENT :

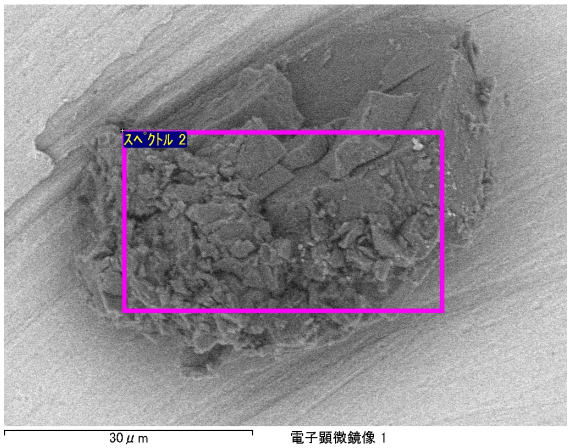


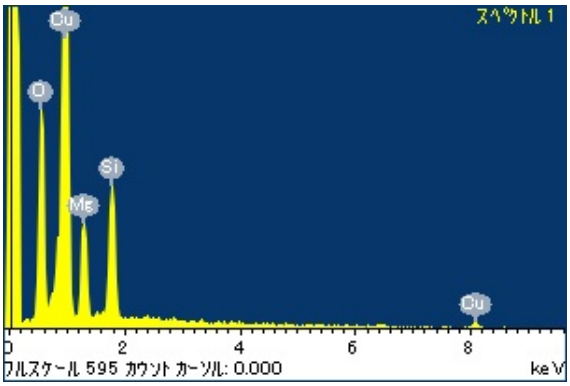



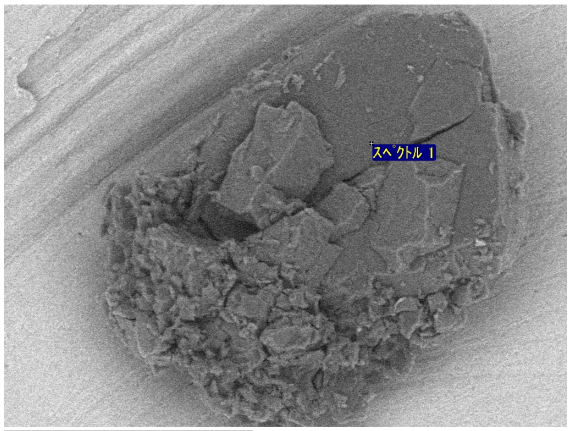



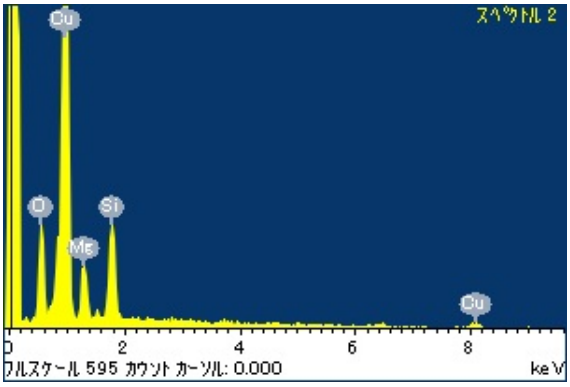



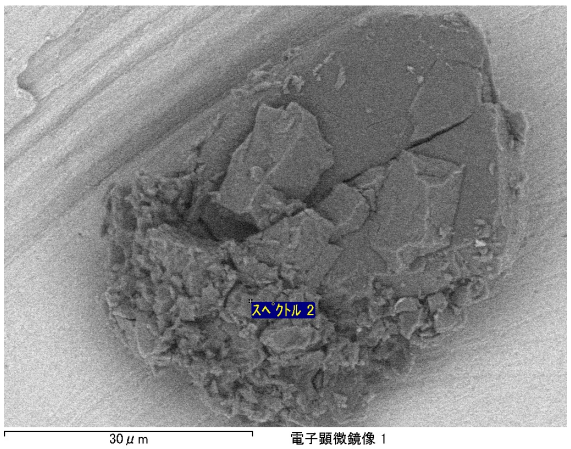





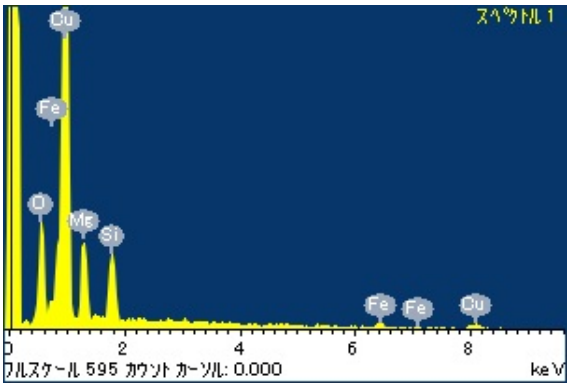



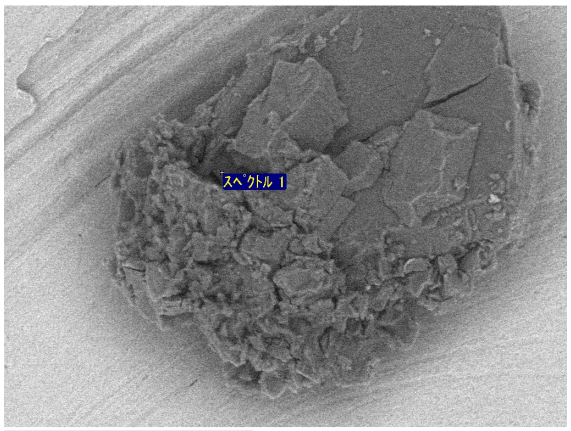

30 μm 電子顕微鏡像 1



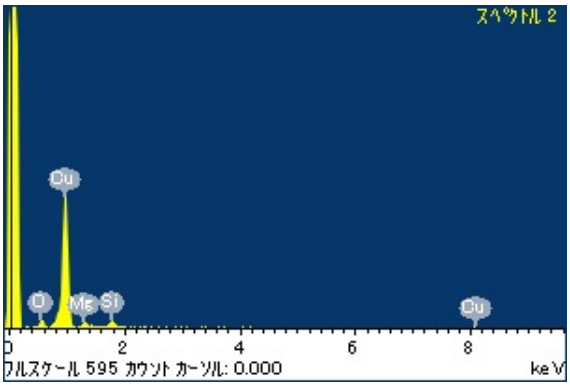



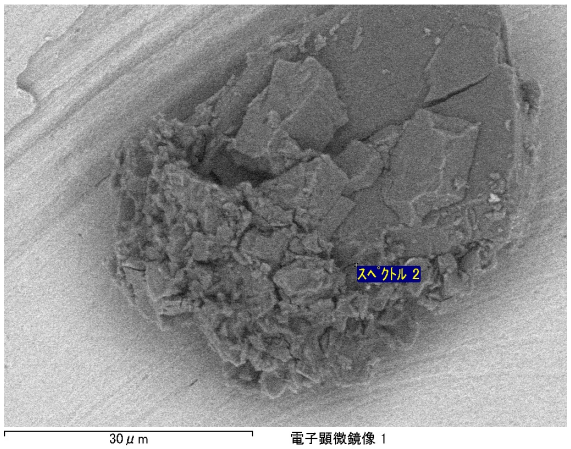

30 μm 電子顕微鏡像 1

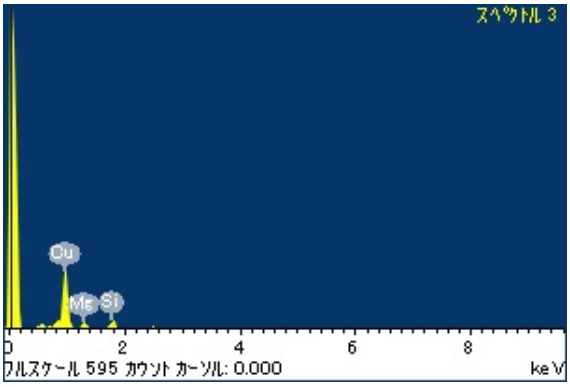



30 μm 電子顕微鏡像 1


ｽﾍﾟｸﾄﾙ 2
Cu
O
Mg
Si
Cu
0
2
4
6
8
ﾌﾙｽｹｰﾙ 595 ｶｳﾝﾄ ｶｰｿﾙ: 0.000
keV


ｽﾍﾟｸﾄﾙ 2
30 μm
電子顕微鏡像 1


ｽﾍﾟｸﾄﾙ 3
Cu
Mg
Si
0
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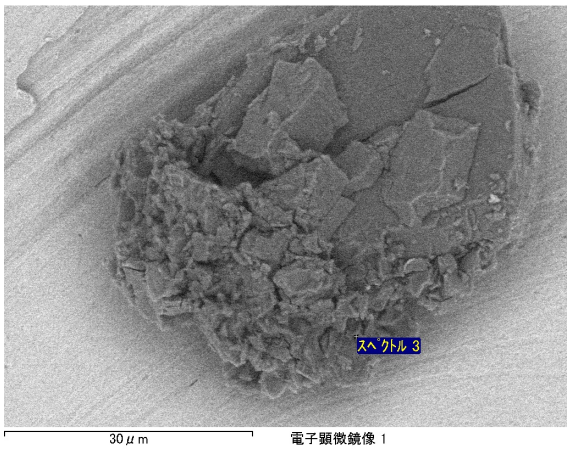
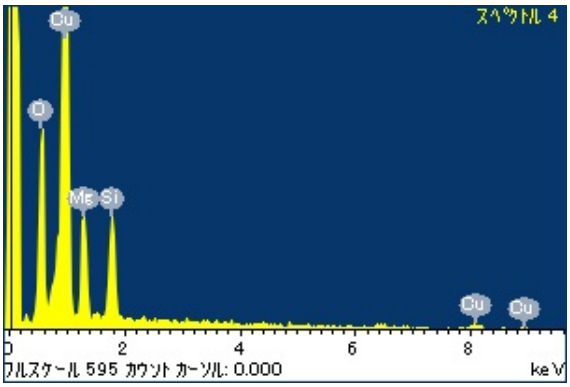
ﾌﾙｽｹｰﾙ 595 ｶｳﾝﾄ ｶｰｿﾙ: 0.000
keV


ｽﾍﾟｸﾄﾙ 3
30 μm
電子顕微鏡像 1


ｽﾍﾟｸﾄﾙ 4
Cu
O
Mg
Si
Cu
Cu
0
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4
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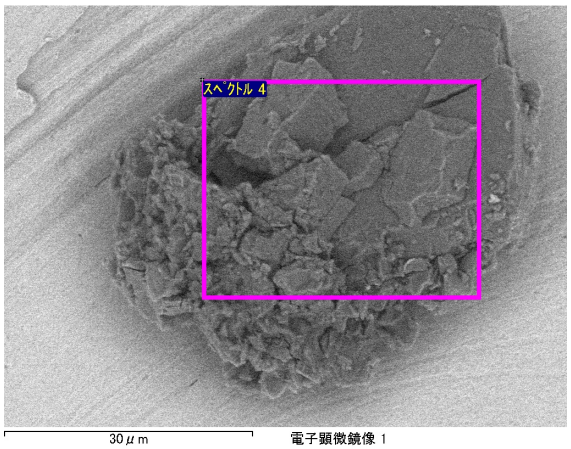
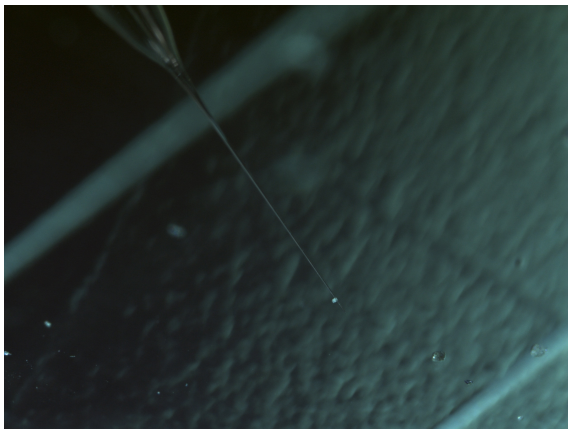
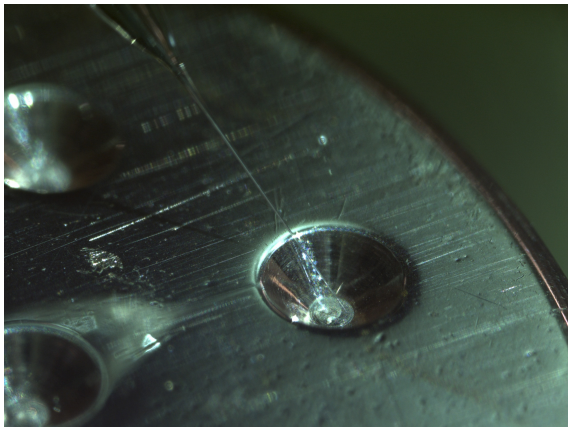
ﾌﾙｽｹｰﾙ 595 ｶｳﾝﾄ ｶｰｿﾙ: 0.000
keV


ｽﾍﾟｸﾄﾙ 4
30 μm
電子顕微鏡像 1



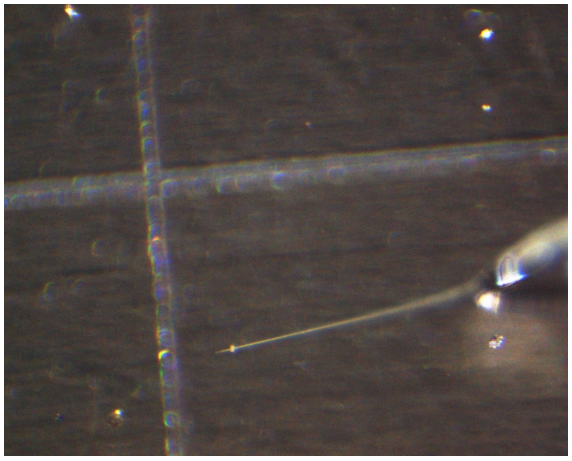
20101205/QD02toCuHolder_toAu/nikon/20101205150741259.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : pick up from QD02
OPERATOR : Noguchi
COMMENT :



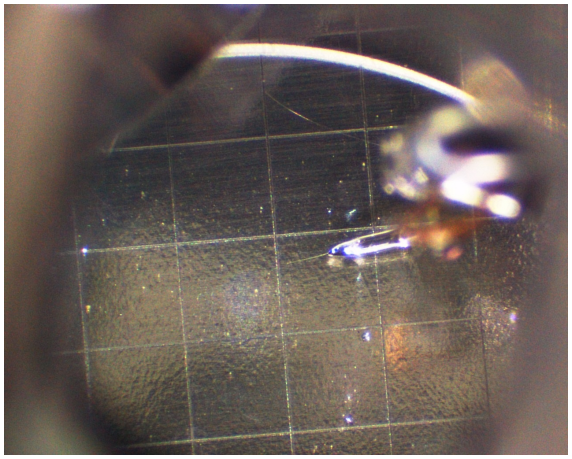
20101205/QD02toCuHolder_toAu/nikon/20101205151326180.bmp

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : release to Cu SEM holder hole17
OPERATOR : Noguchi
COMMENT :



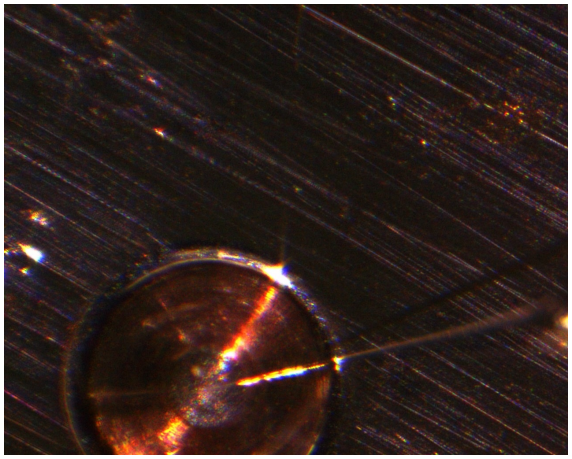
20101205/QD02toCuHolder_toAu/union/unid10pickup.jpg

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : pick up from QD02
OPERATOR : Noguchi
COMMENT :



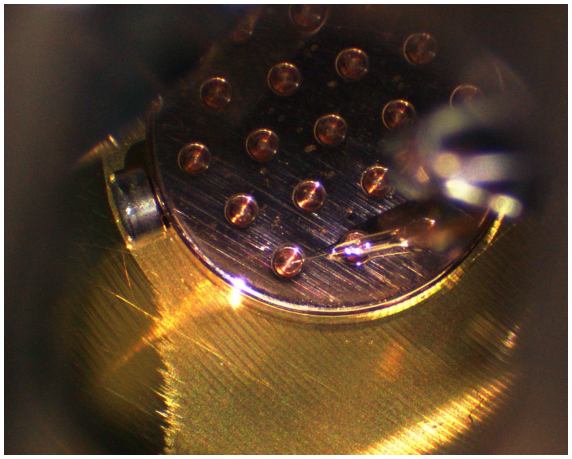
20101205/QD02toCuHolder_toAu/union/unid10pickup_wide.jpg

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : pick up from QD02
OPERATOR : Noguchi
COMMENT :



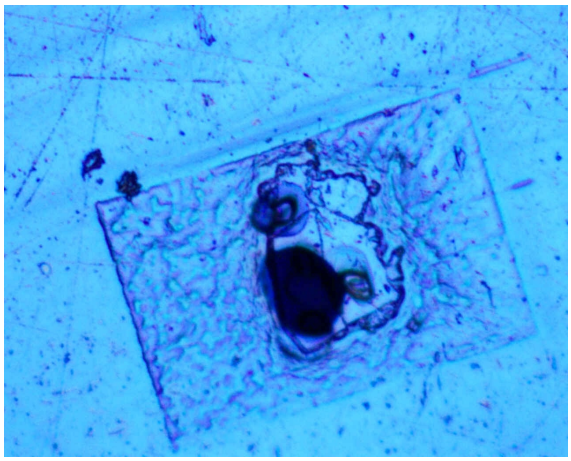
20101205/QD02toCuHolder_toAu/union/unid10release.jpg

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : release to Cu SEM holder hole17
OPERATOR : Noguchi
COMMENT :



20101205/QD02toCuHolder_toAu/union/unid10release_wide.jpg

SAMPLE : RA-QD02-0022
PREID : unID10
PROCESS : release to Cu SEM holder hole17
OPERATOR : Noguchi
COMMENT :



20120221/TEMreturnSamplecheck/20120221/RA-QD02-0022x500.jpg

SAMPLE : RA-QD02-0022
PREID :
PROCESS : condition check after initial analysis
OPERATOR : Yada, Uesugi
COMMENT :